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Hiden ESPion

Advanced Langmuir Probe for Plasma Diagnostics & Characterisation







Applications

- ESPion systems are offered with a range of standard plasma sampling options to provide a non invasive sampling interface for a broad range of plasma applications including:
- ECR- Electron Cyclotron Resonance
- HIPIMS
- Magnetron Discharge
- Helicon Source
- DC Glow Discharge Plasma
- Pulsed Plasma & Laser Ablation
- Parallel Plate RF Plasma
- ICP- Inductively Coupled Plasma.





Data Available

- Floating Potential, V_f
- Plasma Potential, V_{p.}
- Electron Energy Distribution Function, EEDF.
- Debye length, $\lambda_{D.}$
- Ion Flux, Γ_i
- Electron Temperature, Te, up to 10 eV.
- Orbital motion Limited (OML) and Allen Boy Reynolds (ABR)
- Ion density, N_i , and electron density, N_e , over the range 10¹⁴-10¹⁹ m⁻³





RF and DC Probes

- Probes available for both RF an DC plasmas.
- Two probe types available:
 - RF/DC for RF and DC Plasmas.
 - DCHT for DC and High Temperature Plasmas.





Configuration





Probe Tips



Cylindrical Probe Tip



Planar Probe Tip

- More than 20 tip materials available, including Tungsten, Platinum, Molybdenum and Tantalum.
- Tip Types available:
 - Cylindrical
 - 90° for magnetically confined plasmas and plasma mapping.
 - Planar for Hall Thruster Discharges.
- Easily user replaceable.





ESPionSoft Software

- Manual, semi-automatic and fully automatic data analysis data.
- Specific plasma probe data functions for the extraction of plasma parameters.
- Multiple graph displays and multiple files open simultaneously.
- Standard math operations on data curves (add, average, smooth, differentiate).
- Data curves may be combined mathematically, including a scan averaging feature.
- Per scan report of calculated plasma parameters including analysis statistics, slopes and intercepts.



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Scan Set up

- Intuitive setup using the 'Setup Wizard'.
- A wide range of data acquisition parameters can be selected including:
 - Start/ stop potentials.
 - Data averaging and scan period.
 - Probe tip cleaning.
 - Automatic Z-motion steps and range.
 - Signal gating delay and increment timers.







Acquisition Wizard

- Voltage range -200V to +100V, minimum increment 25mV.
- Current range 20µA to 1 A.



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Tip Selection



- Parameters for tip geometry can be selected.
- Allows the use of a range of tip geometries.

	Acquisition Parameters Wize	ard (Default.prm)		×
	Probe Select properties of the probe			
	Probe	10.00		
	Tip Radius	0.075	mm	
	Tip Area	4.73	mm2	
	Impedance	4.90	Ohms	
Advanced	< <u>B</u> ack <u>N</u> ext >	Skip >>	<u>C</u> ancel <u>H</u> elp	

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Automatic Tip Cleaning

- Cleaning potential from -200V to 100V.
- Inter-scan cleaning variable 20ms cleaning and 5ms acquire for 25 ms cycle, or 100ms cleaning and 5ms acquire on 105ms cycle.

	Acquisition Parameters Wizard (Default.prm)
C	Cleaning Select the time and voltage of any pre-scan or in-scan deaning
	Cleaning
	Cleaning Potential 100.00 V
	Duration 100 ms
	 20ms deaning / 5ms data acquisition 95ms deaning / 5ms data acquisition
Advanced	< <u>B</u> ack <u>N</u> ext > Skip >> <u>C</u> ancel <u>H</u> elp





Signal Gating

- Signal gating to synchronise acquisition with a TTL signal.
- The acquisition window can be moved automatically through the pulse.
- Time resolved data is constructed over a number of scans.



Signal Gating



- I-V curve is constructed over many periods.
- By incrementing the delay, time resolved plasma parameters are obtained.





Data Analysis

- Full and Semi-Automatic Analysis of measured parameters.
- Data can be shown as a report or analysis of individual parameters.

Analyse	💹 Create Views - 🗆
Mode Full-automatic Semi-automatic (adjust fit limits as each region is analysed) Options Surface Area 4.73 mm2 Views Molecular Weight 40 m/z Smooth Data before analysing 	View Type Scan report Trend report Electron Energy Distribution (EED) profile Floating potential Plasma potential Electron density Electron temperature I on density Debye length
<u>O</u> K <u>C</u> ancel	<u>Q</u> K <u>C</u> ance

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The I-V Curve

- A. Ion collection
 - (yields $N_i \& \Gamma_i$ "ion flux").
- B. Electron retardation (yields T_e & EEDF).
- **C.** Electron collection (yields N_e).







Electron Energy Distribution Function, EEDF

EEDF is determined by the **Druyvestyn** method, using the second derivative of electron current with respect to voltage 100 from the IV curve attained. Software also provides additional 80 • measurements of: T_e, N_e and EE. EEDF 60 f(E) 40 $f_E(V) = \frac{-4}{A_e^2} \left(\frac{m_e(V_p - V)}{2e} \right)^{1/2} \frac{d^2 I_e(V)}{dV^2}$ 20 0 5 10 15 20 25 30 0 Electron Energy (eV)





Savitzky-Golay Filtering



Typical scan with 5 point filter width.

Typical scan with <mark>25 point</mark> filter width.



 The Savitzky-Golay Filter is used to digitally smooth data and improve the signal to noise ratio without greatly distorting the signal.



RF Compensation



- Component of the RF driving voltage arises between plasma and probe tip distorting probe measurements.
- Removed by AC de-coupling the probe from the DC current measuring circuit and letting tip follow RF fluctuations.
- Hiden Analytical were the first to introduce passive compensation and ESPion has the highest blocking impedance of any commercially available Langmuir probe (wideband compensation).

Chatterton, Rees and Al-Assadi, Vacuum 42 (1991), 489



RF Compensation

- Quality of rf compensation given by the peak separation of the second derivative, d²I/dV², of the I-V characteristic
- Ideal case (perfect compensation) shows no displacement between the positive and negative peaks (both occurring at Vp) in d²I/dV².
- As a practical limit, a difference below 1 Volt is considered excellent for a good rf compensation.





Low Frequency Reference Probe



- Reference probe compensates for low frequency effects:
 - Shift in the plasma potential (e.g. anodised chamber walls).
 - Noise (e.g. power supply).



Application Data - RF Compensation





Application data – Pulsed Plasma



- Gate delay resolution of 125 ns
- Time resolved plasma parameters in an Argon ICP discharge, 500 Hz modulation.



Custom Options





• Manual option available



Custom Options



• 900 mm Auto Linear Drive fully interlocked pneumatic isolation valve.



- 90 degree probes
- Combined linear rotary drives



Selected Users



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Research



esearch	USA	UK/Europe	Asia Pacific	72
	Applied Materials	Bosch	Canon	
RESEARCH	Axelis	IMEC	Hitachi Fundamental Res.	
	CVC/Veeco	Motorola	Hyundai	
ROLLS	DuPont	Nortel Networks	LG Electronics	
	IBM Research	Oxford Plasma Technology	NEC	UNG
	LAM Research	Philips	Samsung	
ROYCE	Lawrence Livermore	Rolls Royce	Sony Corporation	
	Motorola	SGS Thomson	трк Сат	101
	NIST	Siemens	Tokyo Electron	
MOTOROLA	Semetech	Surface Technology Systems	Toshiba SIEM	ENS



- www.HidenAnalytical.com
- The Hiden website is an excellent resource with product pages, brochures, catalogues, product pages with some application notes, presentation and other information.
- Contact +44 1925 445225 for direct support.

